

*45* 36. (New) The method according to claim *43* ~~34~~ further comprising a step of supplying a halogen containing gas into the film formation chamber during heating said organic material.

*b2* *46* 37. (New) The method according to claim *43* ~~34~~ further comprising exposing the vaporized organic material to a plasma.--

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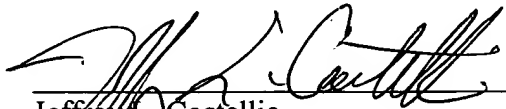
**REMARKS**

Applicants wish to further amend the instant application in addition to the response to the Restriction Requirement and Amendment which was submitted on February 10, 2003.

Specifically, Applicants amend claims 16 and 17 to place them in independent form, and hereby add new claims 18-35 as noted above to recite additional features of the invention to which Applicants are entitled. These claims continue to be directed to elected Group III.

Consideration and allowance of the instant application are now respectfully requested.

Respectfully submitted,

  
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**MARKED-UP VERSION**

IN THE CLAIMS:

16. (Amended) A method of manufacturing an electro-optical device [including the method of cleaning of claim 9] comprising:

irradiating a component provided in a film-forming chamber with at least one selected from the group consisting of infrared light, UV-light, and visible light, thereby sublimating a vapor deposition material adhering to the component; and  
exhausting the sublimated vapor deposition material.

17. (Amended) A method of manufacturing [an electro-optical] a light emitting device [including the method of cleaning of claim 9] comprising:

irradiating a component provided in a film-forming chamber with at least one selected from the group consisting of infrared light, UV-light, and visible light, thereby sublimating a vapor deposition material adhering to the component; and  
exhausting the sublimated vapor deposition material.